

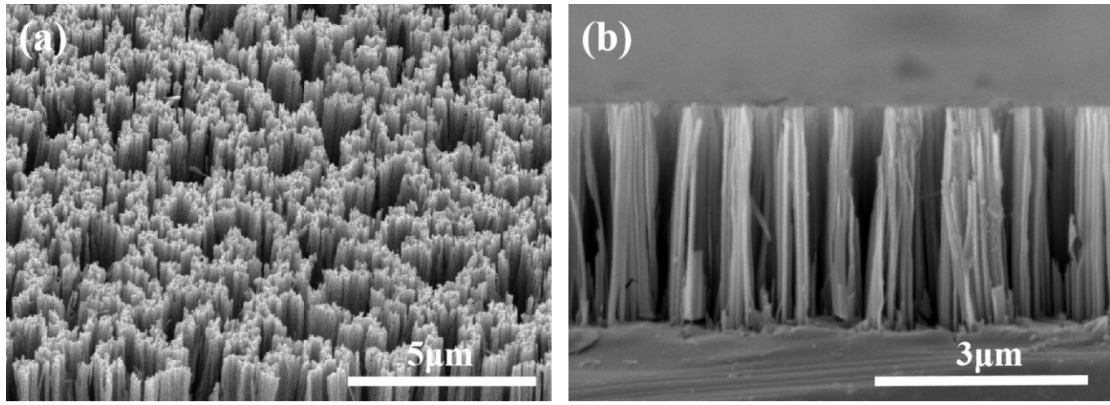
## Supporting information

### **A novel 3D porous electrode of polyaniline and PEDOT:PSS coated SiNWs for low-cost and high-performance supercapacitors**

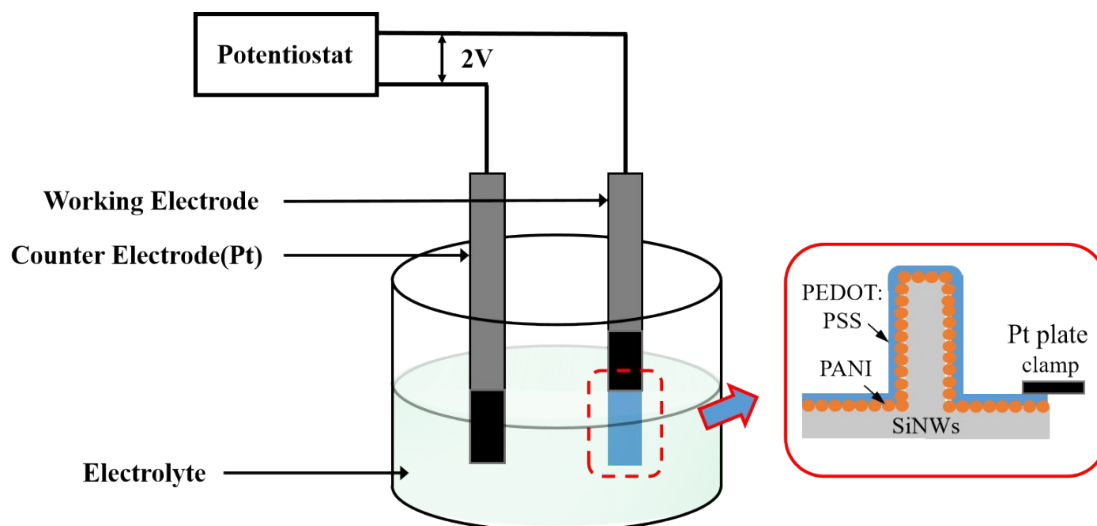
Xiaojuan Shen,<sup>\*a</sup> Xuan Zhang,<sup>a</sup> Tongfei Wang,<sup>a</sup> Songjun Li,<sup>\*a</sup> Zhaoqiang Li<sup>\*b</sup>

<sup>a</sup> *Research School of Polymeric Materials, School of Materials Science & Engineering, Jiangsu University, Zhenjiang, Jiangsu Province, 212013, China.*

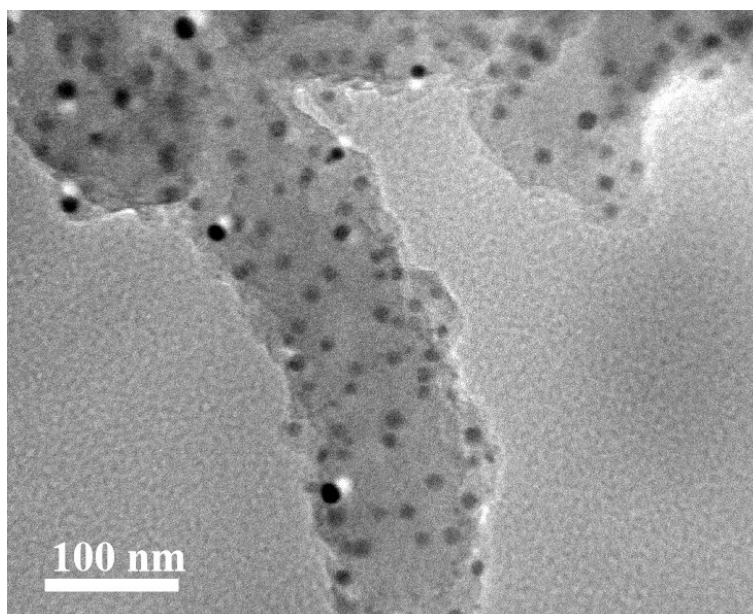
<sup>b</sup> *Department of Chemical Engineering, University of Waterloo, Waterloo, ON N2L 3G1, Canada.*



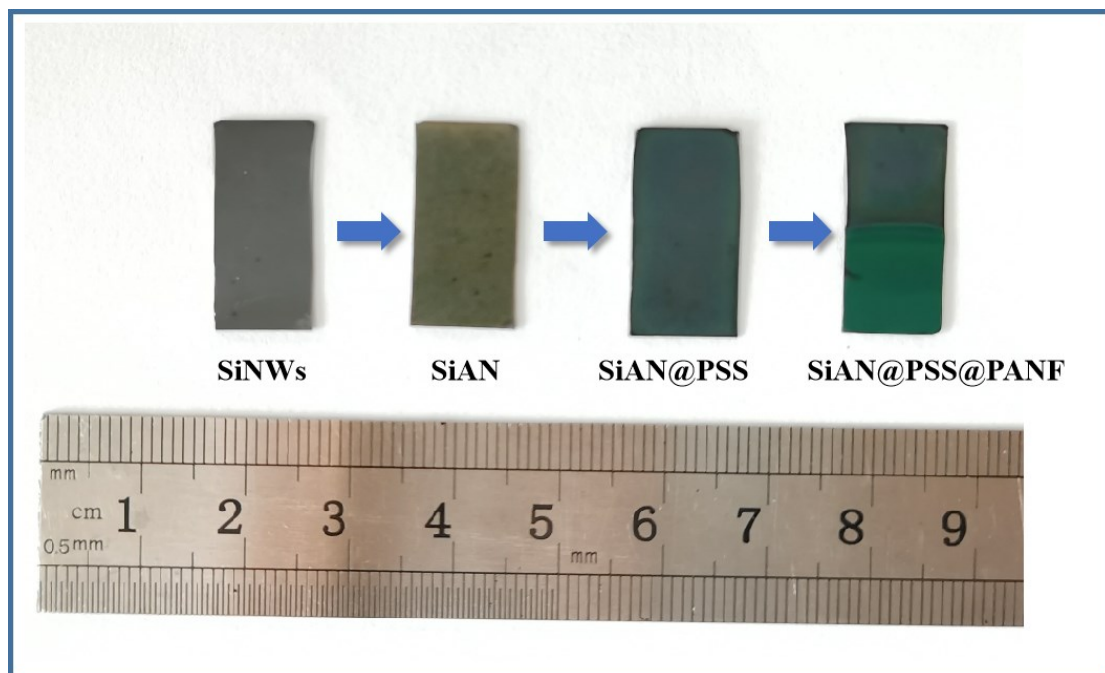
**Fig. S1** SEM image of SiNWs etched by MACE method for 60 min on EG Si wafer from (a) top view and (b) cross-section.



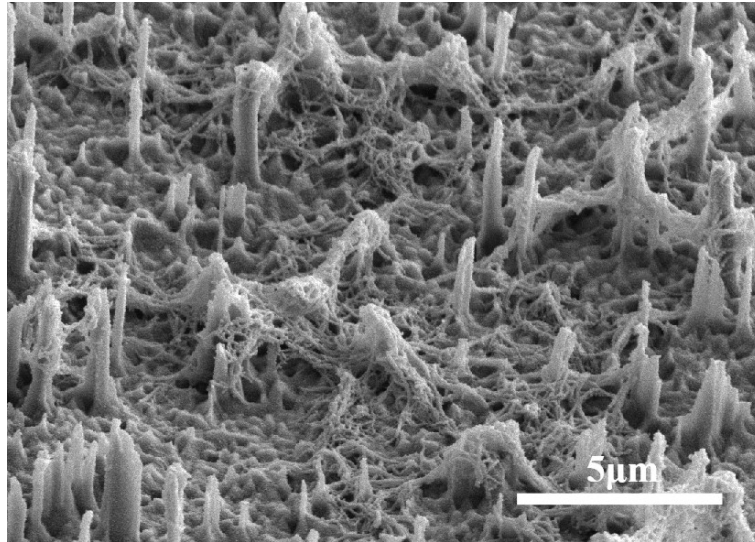
**Fig. S2** Schematic of the electropolymerization system. The SiAN substrate coated with the PEDOT:PSS layer is used as the working electrode. Pt plate clamp connects with the surface where PANI and PEDOT:PSS decorate on the SiNWs substrate.



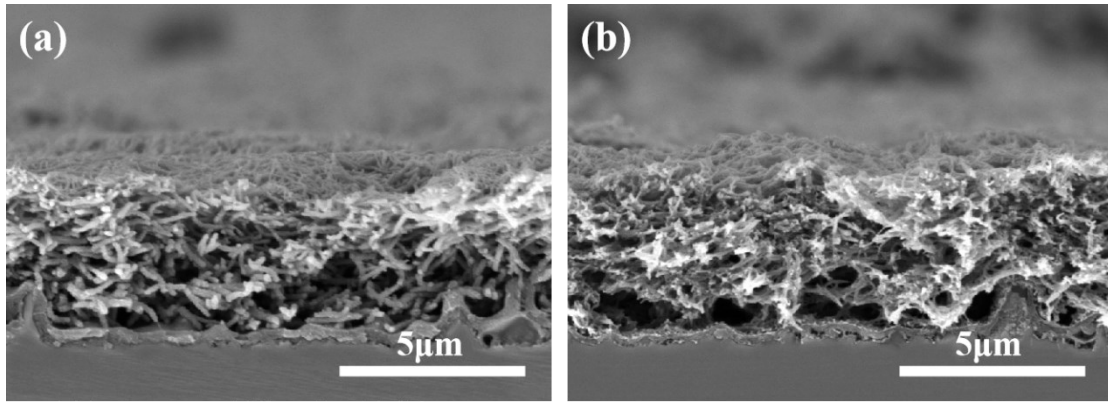
**Fig. S3** TEM image of PANF.



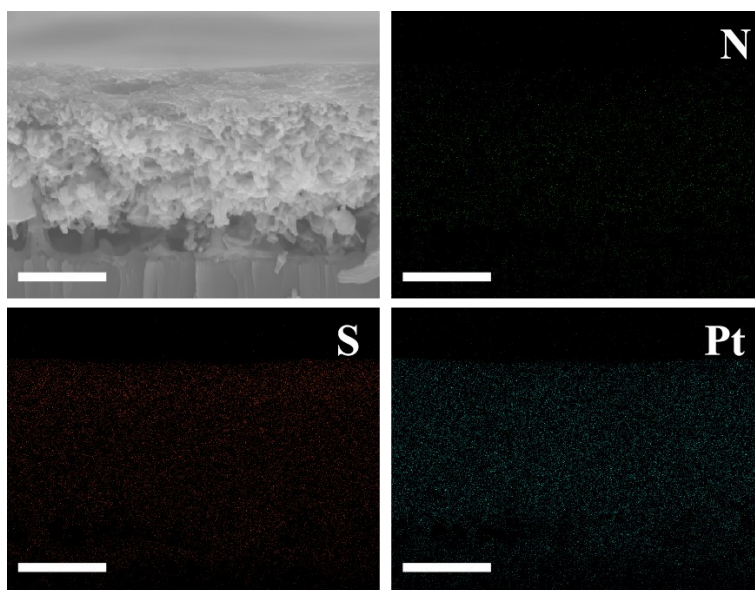
**Fig. S4** Photographs of the different fabricated Si substrates. The deposition time of PANF is 5 min.



**Fig. S5** SEM image of polyaniline electrodeposited on the naked SiNWs substrate using the Ag as the rear electrode with the electrodeposition time of 10 min.

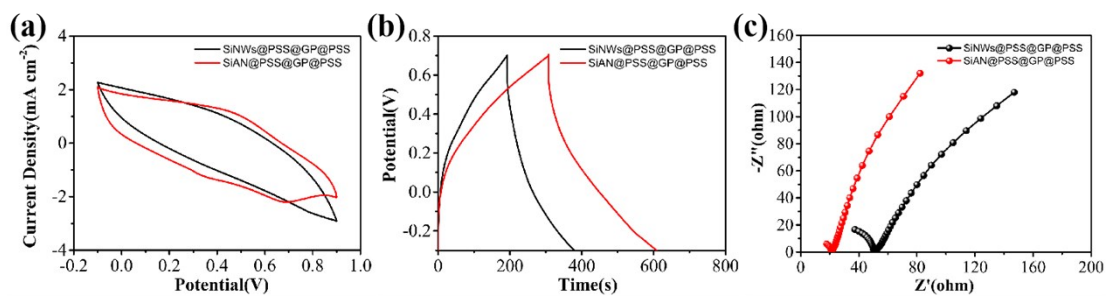


**Fig. S6** Cross-section SEM images of PANF synthesized on the SiAN@PSS substrates incorporated (a) without and (b) with graphene.

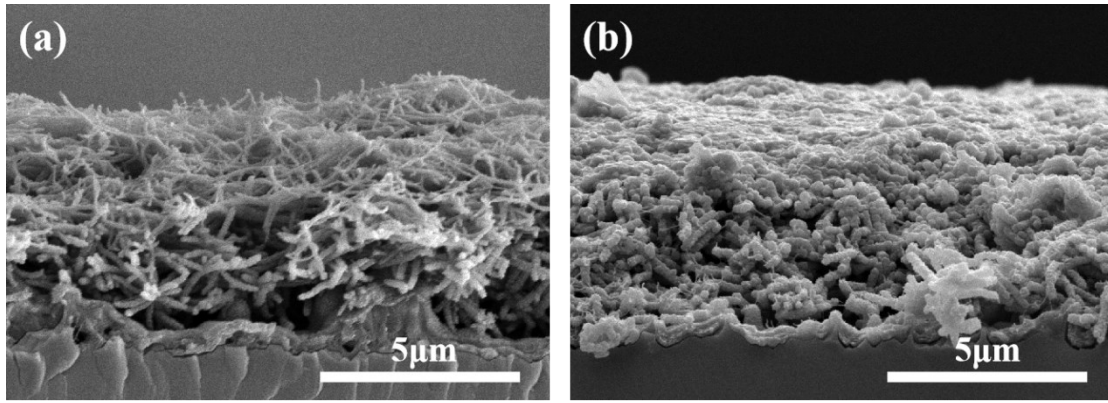


**Fig. S7** SiAN@PSS@GP coated with  $\text{H}_2\text{PtCl}_6$  doped PEDOT:PSS layer and the corresponding cross-section element mappings of N, S and Pt. The electrodeposition time of GP is 8 min. The scale bar is 5  $\mu\text{m}$ .

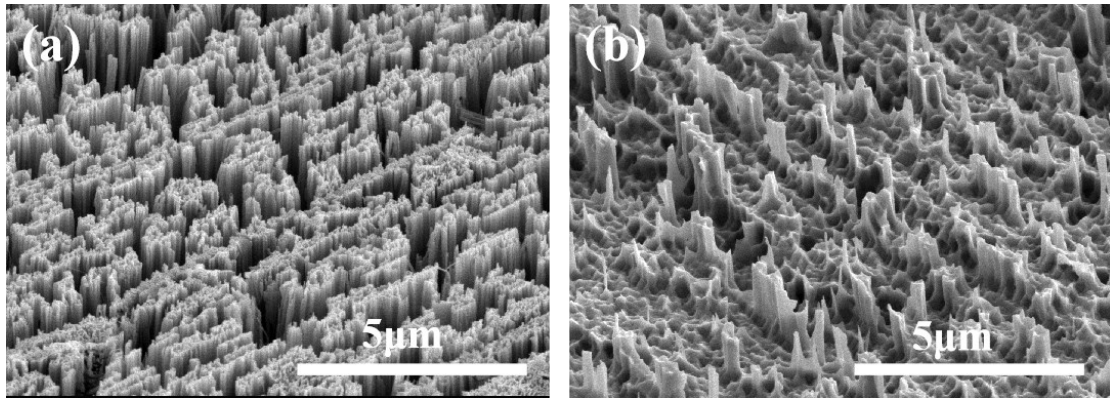




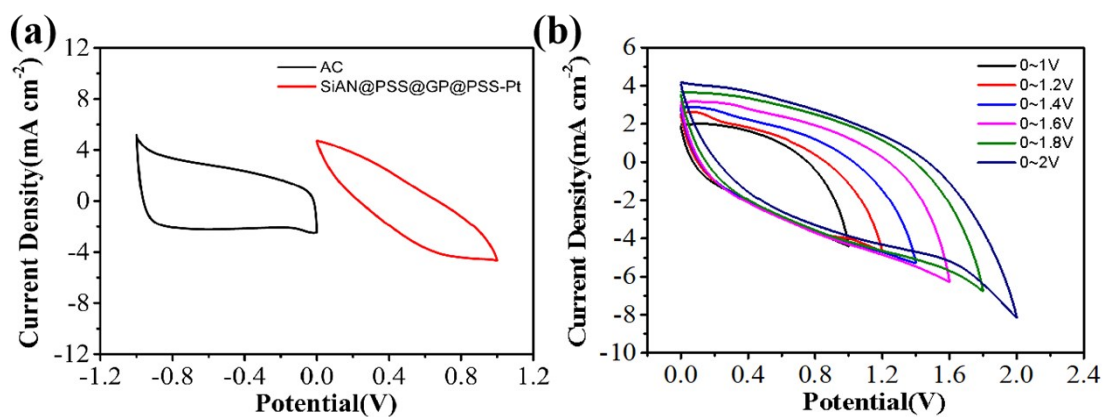
**Fig. S8** (a) CV curves measurement at  $10 \text{ mV s}^{-1}$ , (b) GCD measurement at the current density of  $1 \text{ mA cm}^{-2}$  and (c) Nyquist plots of the electrodes fabricated with PANI (SiAN@PSS@GP@PSS) and without PANI (SiNWs@PSS@GP@PSS) between the PEDOT:PSS and SiNWs. The electrodeposition time is 8 min.



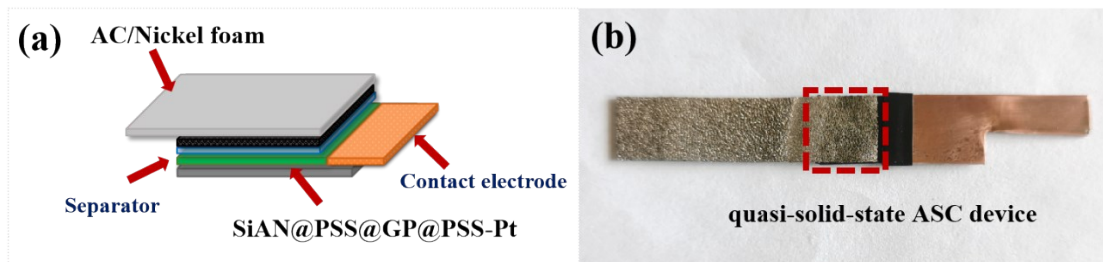
**Fig. S9** The cross-section SEM images of PANF synthesized on (a) SiAN@PSS substrate and (b) SiNWs@PSS substrate.



**Fig. S10** SEM images of (a) pristine SiNWs synthesized from SG Si wafer with MACE method for 30 min, (b) SiNWs treated by TMAH solution for 40 min.



**Fig. S11** (a) CV curves obtained for AC and SiAN@PSS@GP@PSS-Pt electrodes at the scan rate of  $10 \text{ mV s}^{-1}$  and (b) the corresponding CV curves of the ASC in aqueous electrolyte for different potential windows at a scan rate of  $20 \text{ mV s}^{-1}$ .



**Fig. S12** (a) A schematic illustration of the fabricated quasi-solid-state ASC device and (b) an optical image of the device.

**Table S1** Capacitance comparison of SiAN@PSS@GP@PSS-Pt electrode with the previously reported on-chip supercapacitor electrodes using 3D Si nanostructure.

Type	Electrode material	Si growth	Capacitance (mF cm <sup>-2</sup> )	Test Condition	Device configuration	Electrolyte	Refs
1	SiNWs	CVD	0.046	50mV s <sup>-1</sup> ,0.7V	2-electrode	IL/PC <sup>(a)</sup>	1
	SiNWs	CVD	0.013	100mV s <sup>-1</sup> ,1.5V	2-electrode	IL	2
	SiNTrs	CVD	0.35	1mA cm <sup>-2</sup> ,4 V	2-electrode	IL	3
	Oxidized-SiNWs	Etching	0.404	50mV s <sup>-1</sup> ,1.5V	3-electrode	IL	4
	SiNWs/PEDOT	CVD	9	0.1mA cm <sup>-2</sup> ,1.5V	2-electrode	IL	5
	PEDOT@SiNWs	Etching	115	0.5mA cm <sup>-2</sup> ,1V	3-electrode	IL	6
			39.2	0.25mA cm <sup>-2</sup> ,1V	2-electrode		
			14	1mA cm <sup>-2</sup> ,1.5V	2-electrode	IL	7
	SiNTrs/PPy	CVD	19	5mV s <sup>-1</sup> ,1V	3-electrode	Na <sub>2</sub> SO <sub>4</sub>	8
			6.5	2mV s <sup>-1</sup> ,1V	2-electrode	PVA/H <sub>2</sub> SO <sub>4</sub>	
2	SiNWs/MnO <sub>2</sub>	CVD	13	0.4mA cm <sup>-2</sup> ,2.2V	3-electrode	LiClO <sub>4</sub> -IL	9
In <sub>2</sub> O <sub>3</sub> /mesoporous Si	CVD	1.36	10mV s <sup>-1</sup> ,1.2V	3-electrode	Na <sub>2</sub> SO <sub>4</sub>	10	
		25.64	0.1mA cm <sup>-2</sup> ,0.7V	3-electrode	Na <sub>2</sub> SO <sub>4</sub>	11	
	C@SiNWs	Etching					
	Diamond/SiNWs	CVD	1.9	0.1mA cm <sup>-2</sup> ,4V	2-electrode	IL	12
	rGO-SiNWs	HWCVP	0.24	10μA cm <sup>-2</sup> , 1.3V	3-electrode	IL	13
	C/PSiNWs	Etching	190	1mA cm <sup>-2</sup> , 0.8V	3-electrode	IL	14
	Si@Ti@TiN	Etching	43.8	1mA cm <sup>-2</sup> ,0.8V	2-electrode	H <sub>2</sub> SO <sub>4</sub>	15
3	PEDOT/D@SiNWs	CVD	9.5	0.1mA cm <sup>-2</sup> ,2.5V	2-electrode	IL	16
			106	0.5mA cm <sup>-2</sup> ,1.5V	3-electrode	IL	17
	SiNWs/PEDOT@PPy	Etching	46.5	0.5mA cm <sup>-2</sup> ,1.5V	2-electrode		
	Al <sub>2</sub> O <sub>3</sub> /PEDOT:PS S /SiNWs	CVD	8.4	20mV s <sup>-1</sup> ,1.2V	3-electrode	Na <sub>2</sub> SO <sub>4</sub>	18

SiNWs/C/MnOx	Etching	381	12.5mA cm <sup>-2</sup> , 2.95V	3-electrode	IL	19
SiNWs/NC@NiO	Etching	110	1mA cm <sup>-2</sup> , 0.4V	3-electrode	KOH	20
Si-TNR/TiN/MnO <sub>2</sub>	Etching	125	0.2mA cm <sup>-2</sup> , 3.6 V	3-electrode	Na <sub>2</sub> SO <sub>4</sub>	21
		39.7	0.25mA cm <sup>-2</sup> , 0.8V	2-electrode	Na <sub>2</sub> SO <sub>4</sub>	
SiNWs/C/NCO	Etching	1650	3mA cm <sup>-2</sup> , 0.45V	3-electrode	KOH	22
		560	1mA cm <sup>-2</sup> , 0.8V	2-electrode	KOH	
PANI/GNW/SiNWs	Etching	185	10mV s <sup>-1</sup> , 1V	3-electrode	H <sub>2</sub> SO <sub>4</sub>	23
SiAN@PSS@GP	Etching	790.89 (EG)	1mA cm <sup>-2</sup> , 1V	3-electrode	Na <sub>2</sub> SO <sub>4</sub>	This work
@PSS-Pt		718.85 (SG)				

1: Pristine Si, 2: Binary composite, 3: Ternary composite.

(a)IL: ionic liquid, PC: Polycarbonate.

**Table S2** Comparison of energy density and power density of SiAN@PSS@GP@PSS-Pt//AC with the previous reported Si-based devices.

System	Electrolyte	E (mWh cm <sup>-2</sup> )	P (mW cm <sup>-2</sup> )	Refs
Graphene/Si	PYR <sub>13</sub> TFSI	0.004	4	24
PEDOT/PPy/SiNWs	PYR <sub>13</sub> TFSI	0.0146	0.315	17
In <sub>2</sub> O <sub>3</sub> /mesoporous Si	1M Na <sub>2</sub> SO <sub>4</sub>	0.00059	0.03	10
Diamond/SiNWs	PMPyrrBTA	0.00013	0.15	25
Diamond/SiNWs	40%PMPyrrTFSI/PC	0.023	0.94	26
PPy/SiNTrs	PYR <sub>13</sub> TFSI	0.004	0.8	7
Al <sub>2</sub> O <sub>3</sub> /PEDOT:PSS/SiNWs	0.5 M Na <sub>2</sub> SO <sub>4</sub>	0.0023	4.1	18
Ru/SiNWs	0.5 M H <sub>2</sub> SO <sub>4</sub> /PVA	0.035	0.5	27
RuO <sub>2</sub> /SiNWs	H <sub>2</sub> SO <sub>4</sub> /PVA	0.0004	0.03	8
C@SiNWs	1 M Na <sub>2</sub> SO <sub>4</sub>	0.04	0.00175	11
MnOx/C/PSiNW	0.1M EMIM-TFSI	0.555	0.48	19
PEDOT/D/SiNWs	N <sub>1114</sub> TFSI	0.007	1.3	16
GNW/RuOx/Si	H <sub>3</sub> PO <sub>4</sub> /PVA	0.0151	2.49	28
PEDOT coated SiNWs	N <sub>1114</sub> TFSI	0.0092	0.11	6
Graphene/PANI/SiNWs	1M H <sub>2</sub> SO <sub>4</sub>	0.0117	0.42	29
SiAN@PSS@GP@PSS-Pt	1M Na <sub>2</sub> SO <sub>4</sub>	0.194	0.850	This work
//AC	PVDF-HFP/IL	0.063	0.801	



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